

# Process Development and Integration Lab + Measurements and Characterization

## PDIL Presentations

PDIL Introduction

Thin-Si Platform

Si Wafer Replacement Platform

CIGS Platform

CdTe Platform

Atmospheric Processing Platform

M&C Platform and Standalone Capabilities

Data Integration

M&C Overview



**Austin Airport Marriott South**

**Austin, TX April 22-24, 2008**



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# 2008 Solar Annual Review Meeting

## PDIL Overview

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Brent P. Nelson

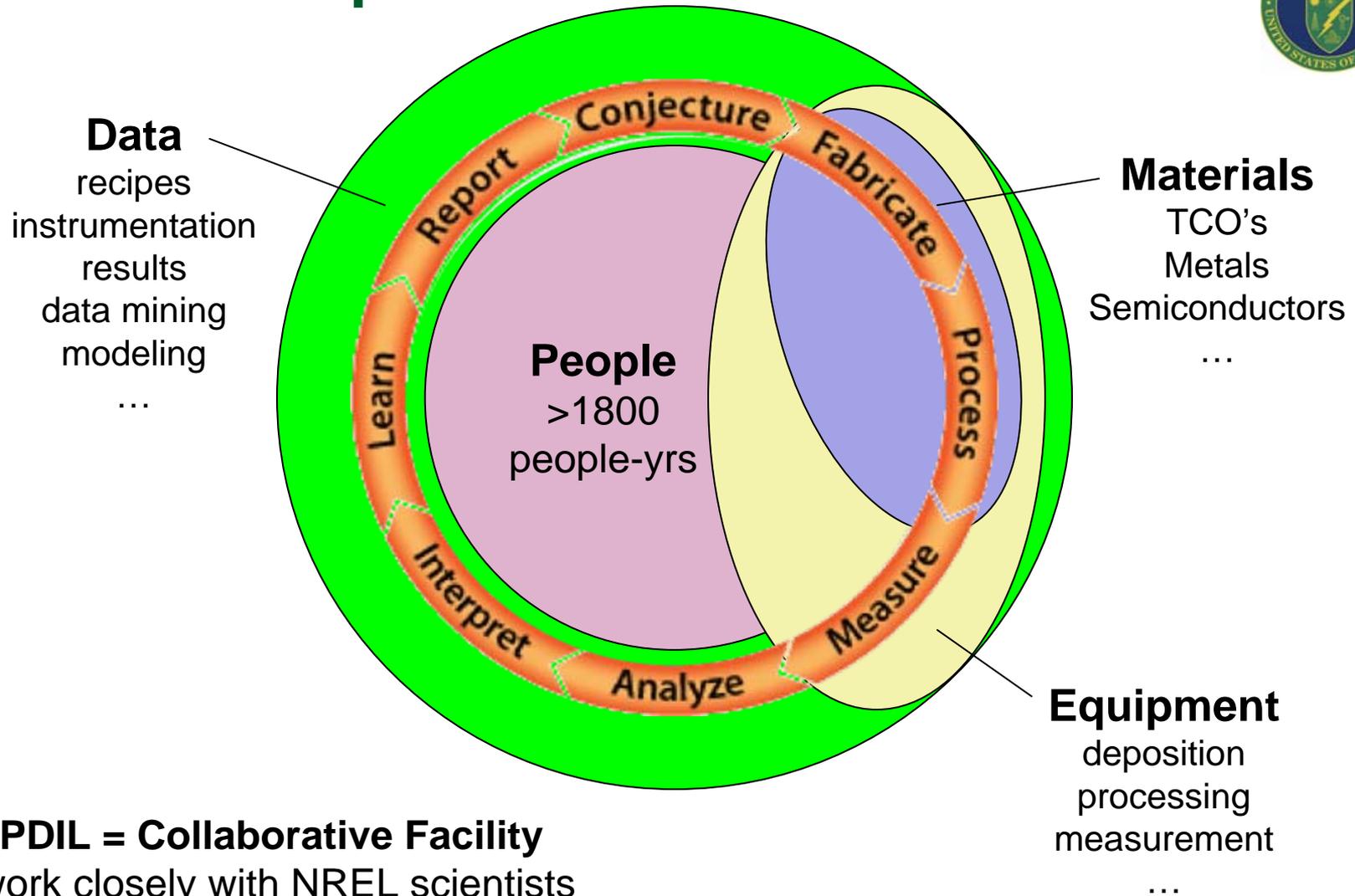


# PDIL Vision



- Integrate deposition, characterization, and processing
  - Flexible and robust
  - Standardized transfer interface
  - Controlled sample ambient between tools
- Benefits
  - Answers to previously inaccessible research questions
  - Control and characterization of critical surfaces (interfaces) and how their impact on subsequent layers
  - Assess process-related source chemistry, surface chemistry and kinetics, and bulk reconstruction
  - Grow layers and alter interfaces using controlled processes and transfer ambients (without exposure to air)
  - Develop new techniques, methodologies, device structures, materials, and tools (growth, processing, and analytical)
  - Improved collaborations with university and industry researchers

# PDIL Concept



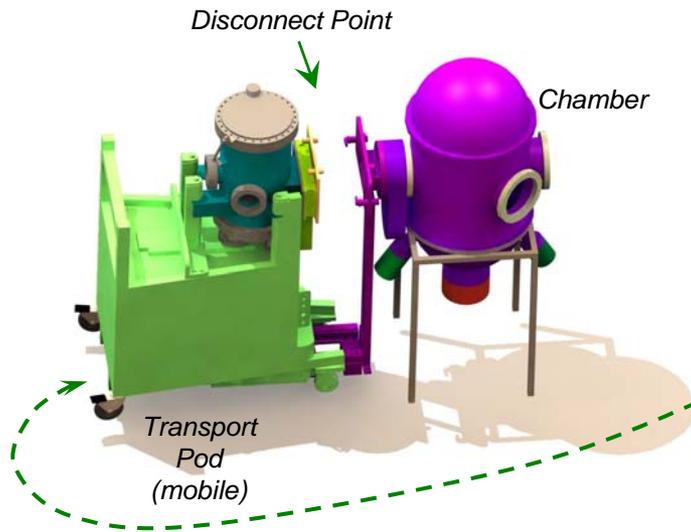
## The PDIL = Collaborative Facility

- work closely with NREL scientists
- integrated equipment
- answer pressing PV related questions

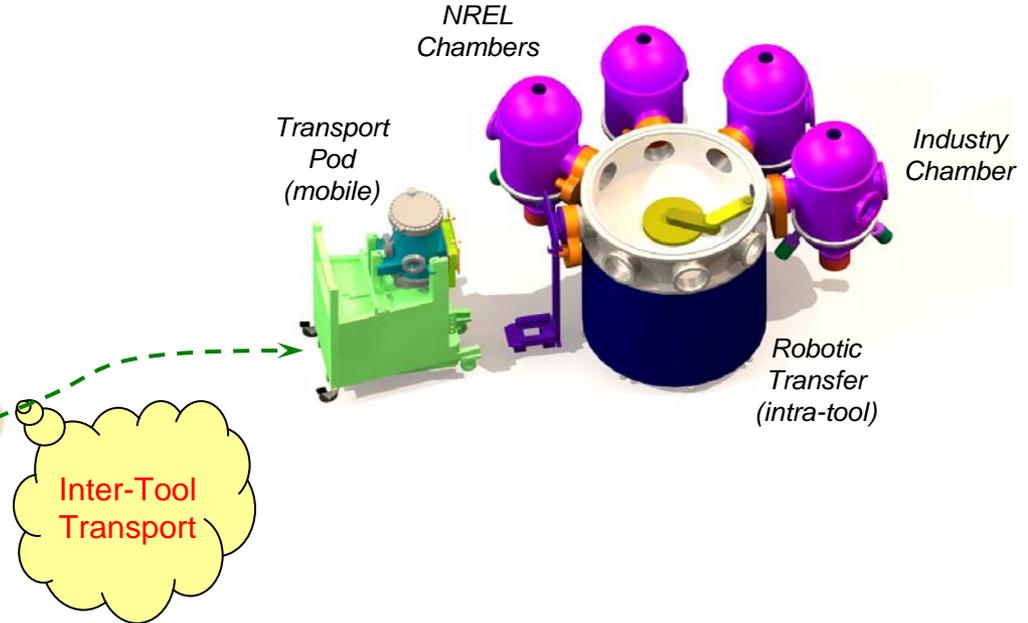
# PDIL Implementation



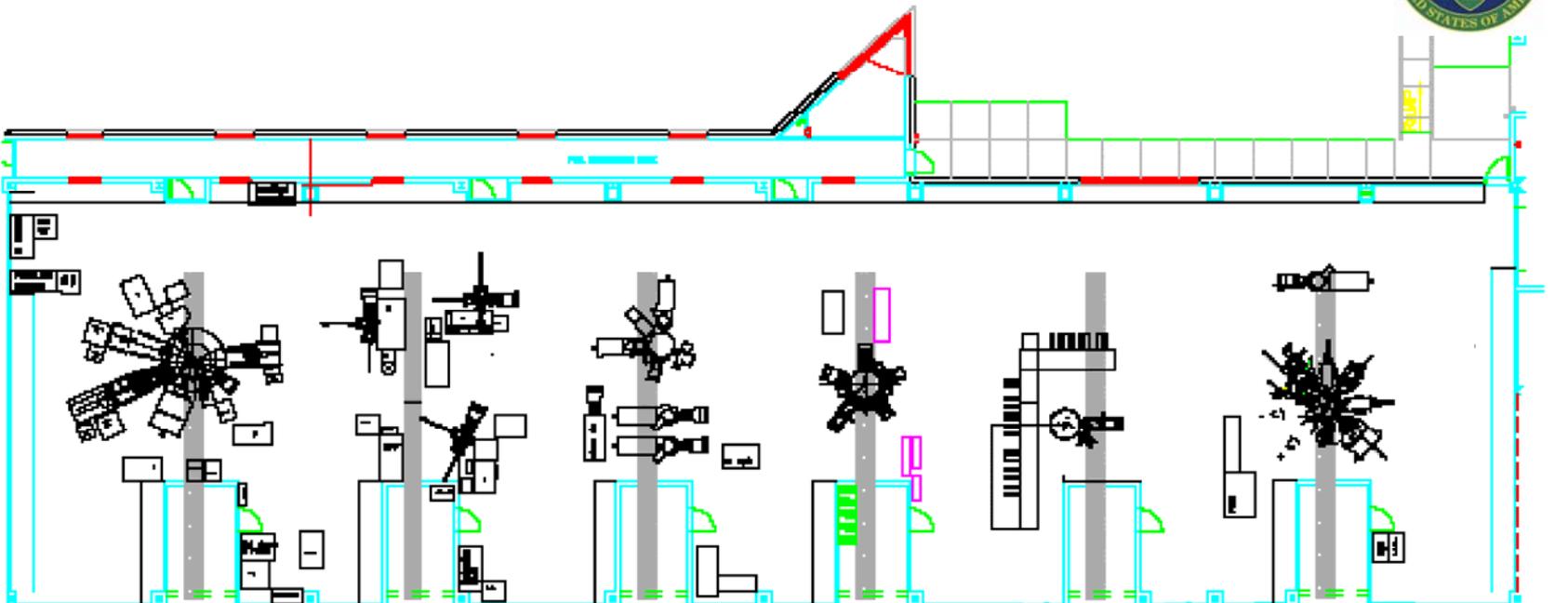
## Stand-Alone Tools



## Platform: Robotic Transfer



# PDIL Equipment Platforms



1) CIGS Platform

2) Atm. Processing

3) Silicon Platform

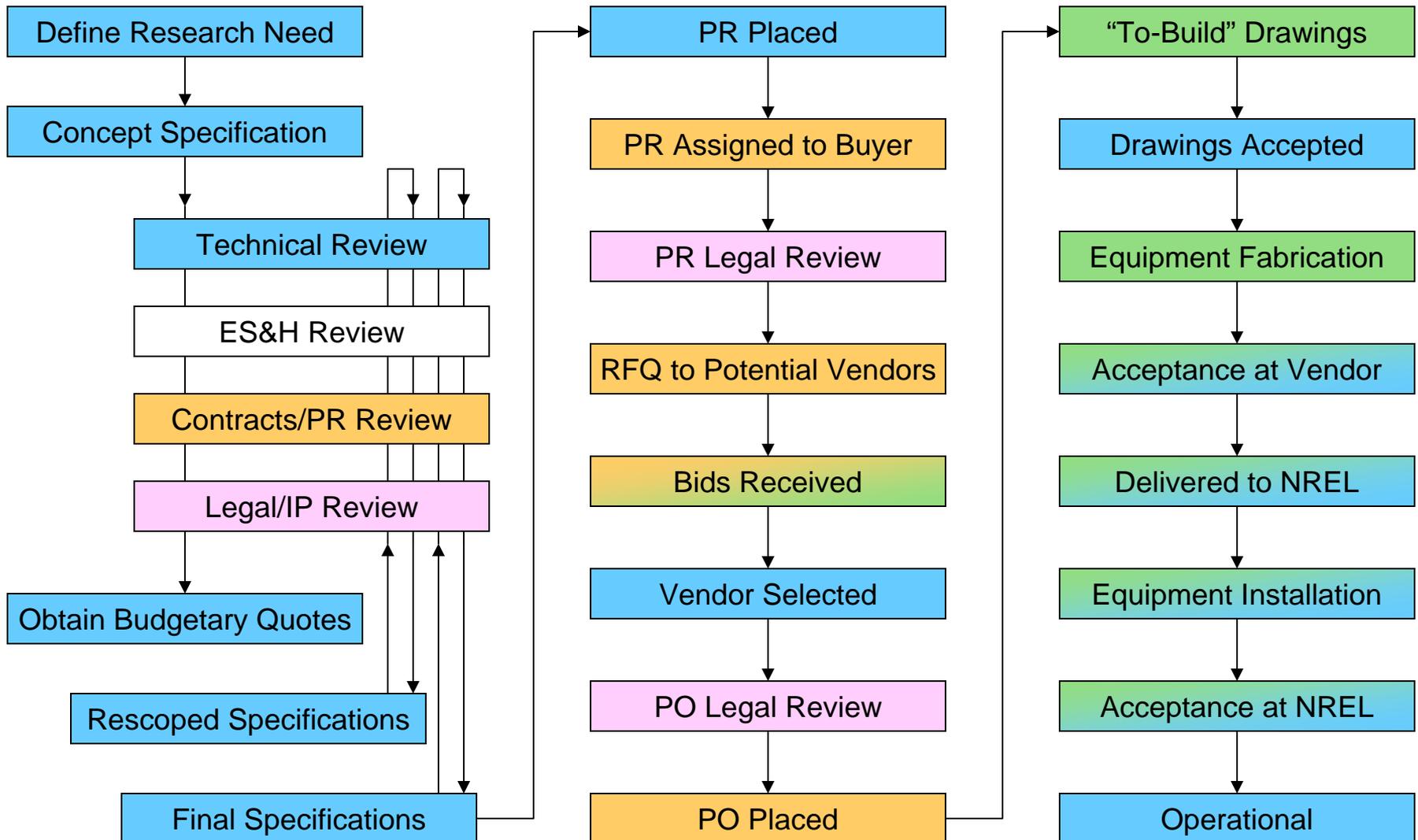
4) Si / CdTe

5) M&C Stand-Alone

6) M&C Integrated



# Steps in Custom Equipment Acquisition





# Thin-Silicon Platform

Qi Wang



		PV Technology Road Maps						
Platform		Wafer Si	Film Si	CPV	CdTe	CIGS	OPV	DSPV
Thin Si		■	■					
Wafer Rep.		■	■					
CIGS						■		
CdTe					■			
Atm. Proc.		■	■		■	■	■	■
M&C Ind.		■	■	■	■	■	■	■
M&C Cluster		■	■	■	■	■	■	■